

(19)



(11)

EP 3 384 849 A1

(12)

EUROPEAN PATENT APPLICATION

(43) Date of publication:
10.10.2018 Bulletin 2018/41

(51) Int Cl.:
A61B 8/00 (2006.01) **G10K 11/20 (2006.01)**
B06B 1/06 (2006.01) **G10K 11/02 (2006.01)**

(21) Application number: **17165437.9**

(22) Date of filing: **07.04.2017**

(84) Designated Contracting States:
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR
 Designated Extension States:
BA ME
 Designated Validation States:
MA MD

(72) Inventors:
 • **Palchetti, Paolo**
50135 Firenze (IT)
 • **Grandoni, Andrea**
50036 Vaglia (FI) (IT)
 • **Cuseri, Iolanda**
52043 Castiglion Fiorentino (AR) (IT)

(71) Applicant: **Esaote S.p.A.**
16152 Genova (IT)

(74) Representative: **Bessi, Lorenzo**
Esaote S.p.A.
via di Caciolle, 15
50127 Firenze (IT)

(54) **ULTRASOUND PROBE WITH ACOUSTIC AMPLIFIER**

(57) A transducer assembly operable to transmit ultrasonic energy in a desired direction towards a zone adapted to be acoustically coupled to an object or area of interest, the assembly comprising:

- a transducer layer;
- a backing material disposed behind said transduction material with respect to the desired direction;
- a back-matching layer disposed between the transducer layer and the backing material to reflect towards said

transducer layer part of the ultrasonic energy directed from the transducer layer to the backing material.

The back-matching material has an impedance less than the impedance of the transducer layer and the transducer layer has a thickness greater than a 1/4 of the wavelength of the ultrasound waves the assembly is configured to generate. A process for manufacturing a transducer assembly is also disclosed.

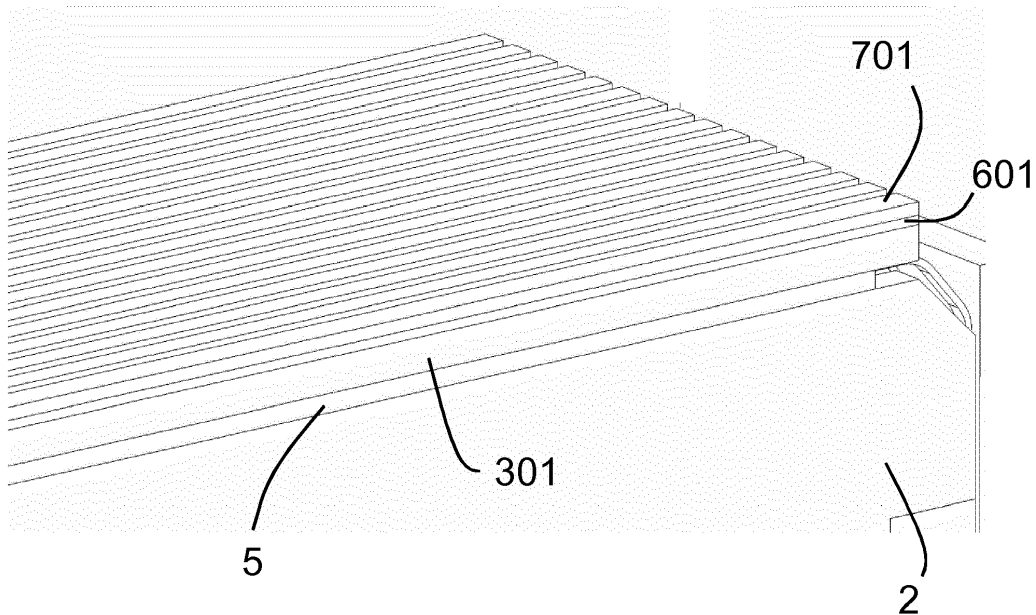


Fig. 5

EP 3 384 849 A1

Description

FIELD OF THE INVENTION

5 **[0001]** The invention relates to the technical field of ultrasound probes, particularly in the medical field, although it can find applications also in the nondestructive testing field.

STATE OF THE ART

10 **[0002]** Ultrasound diagnostic technology generally relates to imaging of biological tissue using an ultrasonic transducer probe. The probe includes a transducer which transmits ultrasonic waves and receives ultrasonic echoes reflected from the tissue. The transducer is typically placed on the body surface or internal to a body lumen of a patient in a selected imaging region. The ultrasound transducer generates and directs ultrasonic waves to the imaging region. The transducer then receives ultrasonic waves reflected from the region and converts the received waves into electrical signals that are
15 processed to form a diagnostic image.

[0003] Ultrasound transducers typically have several acoustical stacks or layers arranged in one dimension or in two-dimensional (2D) arrays from the furthest (back) to the closest (front) to the area to be placed in contact with the skin and in more in general with the surface of the object to be analysed.

20 **[0004]** One or more of these layers comprise piezoelectric elements capable of converting a signal into an acoustic wave and vice versa. The remaining layers consist of a backing layer placed between the piezoelectric element and the back of the probe and one or more matching layers located between the piezoelectric elements and the front of the probe.

[0005] From US 6,049,159 it is known to use a further layer positioned at the rear-facing part of the piezoelectric elements, i.e. located between the backing layer and the piezoelectric elements. This layer, hereinafter also referred as back-matching layer or dematching layer, is used to reflect upward part of the energy traveling towards the backing to
25 gain sensitivity.

[0006] Increase of sensitivity requires a large impedance mismatch between the piezoelectric layer and the back-matching layer to have strong reflection and thus relevant back-propagating energy. This can be achieved both using a material for the back matching layer having an impedance Z_{layer} which is much higher than the impedance Z_{Piezo} of the piezoelectric layer or with a material for the back matching layer having an impedance Z_{layer} which is much lesser
30 than the impedance Z_{Piezo} of the piezoelectric layer following the well-known formula

$$35 \quad \text{Reflection} = \frac{Z_{layer} - Z_{Piezo}}{Z_{layer} + Z_{Piezo}} \quad (\text{eq.1})$$

[0007] According to the document above, the choice of the impedance of the back-matching layer is critical and has to be carefully done to allow the reflection only of a selected portion of the backwards propagating acoustic energy as bandwidth, sensitivity and pulse duration have contrasting requirements for such an impedance value. It is, however,
40 not an easy task to determine the best value for the impedance of the back-matching layer to take into account of all of these parameters.

[0008] In document US 7,621,028, the choice of a high acoustic impedance back-matching layer has been adopted to assure high bandwidth, a key parameter of the performance of a transducer. The materials mentioned in this document are typically a Tungsten material; a Tantalum material; a Tungsten Carbide (WC) material; a WC and Cobalt material;
45 a WC, Cobalt and Tantalum Carbide material; a WC, Nickel and Carbide-Molybdenum oxide (Mo2C) material; and a WC, Nickel, Cobalt and Chromium Carbide (Cr3C2) material all of them having acoustic impedance Z higher than 100 MRayl.

[0009] This, however, poses the following drawbacks:

50 High Z materials are not easy to cut and bind as they normally contain metals. High impedance brings to tight requirements for piezoelectric and de-matching roughness. Furthermore, infra-element cutting is necessary due to their electrical conductivity;

At frequency higher than 5 MHz the quality of the contact surface bonding between piezo and back-matching layer is critical;

55 The thickness of the piezo material is $\lambda/4$ that represents a problem for high frequency probes.

[0010] Thus a need continues to exist to determine an appropriate range of values for the impedance of the back-matching layer, and thus for the choice of materials to be used as back matching layer, to increase the sensitivity of the

transducer without significantly affecting the bandwidth and pulse duration.

SUMMARY OF THE INVENTION

5 **[0011]** It is thus an object of embodiments herein to provide a configuration of a transducer assembly with enhanced sensitivity.

[0012] In an embodiment, a transducer assembly operable to transmit ultrasonic energy in a desired direction towards a zone adapted to be acoustically coupled to an object or area of interest comprises:

- 10 a) a transducer layer;
 b) a backing material disposed behind said transduction material with respect to the desired direction;
 c) a back-matching layer disposed between the transducer layer and the backing material to reflect towards said transducer layer part of the ultrasonic energy directed from the transducer layer to the backing material,

15 wherein the back-matching material has an impedance less than the impedance of the transducer layer and the transducer layer has a thickness greater than a 1/4, typically 1/2, of the wavelength of the ultrasound waves the assembly is configured to generate, particularly half of the wavelength.

20 **[0013]** The inventors found that, if the impedance of the back-matching layer is kept very low, for example less than 5 MRayl, particularly between 0.5 and 4 MRayl, typically between 0.6-2 MRayl, more typically between 0.7 and 1 MRayl, for example by using a polymer such as epoxy, powder/particle filled epoxy, polyurethanes, acrylics or the like, bandwidth and pulse length deterioration can be compensated without caring about the acoustic properties of the back matching layer simply using the components already available in common ultrasound transducers, namely the piezoelectric layer and the front matching layers if the thickness of the piezoelectric layer is increased from $\lambda/4$ up to $\lambda/2$.

25 **[0014]** To such extent, in an embodiment, the transducer assembly comprises one or more front acoustic matching layers arranged as a stack starting from the transducer layer towards the coupling zone. The front matching layers have a thickness less than half of the wavelength, particularly not greater than 1/3 of the wavelength, and are configured to compensate for increase in pulse duration of the ultrasound wave directed towards the desired direction caused by the low impedance of the back-matching layer.

30 **[0015]** In this configuration, bandwidth and pulse length can be accommodated by acting on the front matching layers with thickness less than half of the wavelength, particularly not greater than 1/3 of the wavelength, typically in the range 1/4 - 1/6 of the wavelength. The detailed description will provide some examples of that. The result is an increased sensitivity comparable to high impedance matching layer solutions of the prior art without significantly affecting bandwidth and pulse length requirements.

35 **[0016]** Increasing the thickness of the piezoelectric layer simplifies the manufacturing process, particularly for high frequency transducers. Furthermore, working with materials having a low acoustic impedance bring additional unexpected advantages.

[0017] First of all, materials having adhesive properties like epoxy or powder/particle filled epoxy can be used as back matching layer. In terms of manufacturing steps, that means that piezoelectric bonding can be realized together with back-matching layer fabrication.

40 **[0018]** If a material having high acoustic impedance (80-100 MRayl and more) is used, the manufacturing process will require a further step of thin film adhesive deposition to coat the back-matching layer.

[0019] Secondly, the impedance of the back matching material can be finely controlled adopting air bubble/glass microspheres or thermo-expandable microcapsules particles dispersed in liquid polymers like epoxies, polyurethanes, acrylics.

45 **[0020]** The microcapsules can, for example, encapsulate liquid low-boiling-point hydrocarbon in shells of thermoplastic resin like VCl₂-AN copolymer (chlorine containing shell), AN copolymer (chlorine-free shell). When the microcapsules added to the polymer, for example epoxy, are heated, the shells are softened and expanded with the pressure of gasified hydrocarbon while the polymer cures. A microcapsule expand into 50 to 100 times of its original volume (ballooning) and the cured polymer, where the heated microcapsules are dispersed, can have bulk density as small as 0.4 g/cm³ and acoustic impedance of 0.7-0.8 MRayl. Adjusting microcapsules concentration (% in volume) in polymer and curing schedule acoustic impedance can be fine-tuned.

[0021] Impedance lowering can be obtained also adding to the polymer the above microcapsules already expanded prior to use.

55 **[0022]** By the way, what is here presented should be interpreted to embrace the corresponding materials that have been described and their equivalent but not limited to any material types, which can be adopted for the purpose.

[0023] This allows to fine-tune the impedance of the back matching layer as an improvement according to embodiments herein.

[0024] According to an aspect, embodiments also relate to a process for manufacturing a transducer assembly operable

to transmit ultrasonic energy in a desired direction towards a zone adapted to be acoustically coupled to an object or area of interest, the process comprising:

- 5 - providing a transducer layer;
- providing a backing layer;
- providing a back-matching material having acoustic impedance less than the acoustic impedance of the transducer layer, for example comprising one or more polymers, particularly epoxies, polyurethanes, acrylics or the like;
- direct casting the back matching material either on the backing layer to realize a back-matching/backing subassembly or on the transducer layer to realize a transducer/back-matching subassembly;
- 10 - bonding either the transducer layer with the back-matching/backing subassembly or the transducer/back-matching subassembly with the backing layer.

[0025] The process may further comprise:

- 15 - preparing the surface of the transducer layer or of the backing layer for wettability increase and adhesion enhancement of the back-matching material or transducer layer;
- grinding of the back-matching material to a pre-determined thickness.

[0026] According to an embodiment, before direct casting the back-matching material on the backing layer or on the transducer layer, a process comprises:

- 20 - providing air bubble/glass microspheres or thermo-expandable microcapsules;
- adding the microcapsules to the back-matching material;
- mixing the back-matching material with the thermo-expandable microcapsules.

[0027] The process may further comprise curing the back-matching material or the back-matching/backing subassembly or the transducer/back-matching subassembly to control the acoustic impedance of the back-matching material.

[0028] The curing step may be performed at a temperature that allows the microcapsules to expand from 50 to 100 times their original volume to bring the density of the back-matching material less than 0.6 g/cm³, typically in the range 0.3-0.5 g/cm³, more typically equal or less than 0.4 g/cm³ and thus the acoustic impedance of the back-matching material less than 1 MRayl, typically between 0.6-0.9 MRayl, more typically between 0.7-0.9 MRayl. The microcapsules may, for example, encapsulate liquid low-boiling-point hydrocarbon in shells of thermoplastic resin like VC1₂-AN copolymer or AN copolymer.

[0029] Further improvements of the invention will form the subject of the dependent claims.

BRIEF DESCRIPTION OF THE DRAWINGS

[0030] The characteristics of the invention and the advantages derived therefrom will be more apparent from the following description of non-limiting embodiments, illustrated in the annexed drawings, in which:

- 40 Fig. 1 shows a perspective view of a conventional probe according to the state of the art.
- Fig. 2 shows an enlarged view of the head of the probe according to figure 1.
- Fig. 3 schematically shows a probe head with ground wire connections arranged to contact transducer elements of a same row.
- 45 Fig. 4 schematically shows a probe head according to an embodiment.
- Fig. 5 shows an enlarged view of the head of the probe according to Fig. 4.
- Fig. 6 schematically shows a probe head according to another embodiment.
- Fig. 7 shows the sensitivity comparison for various back-matching layer materials, without front matching layers.
- Fig. 8 shows the effect on band of two optimized front matching layers with pure epoxy back-matching layer as low Z amplifier. Comparison is made with the standard structure (the same front matching layers without any back-matching layer).
- 50 Fig. 9 shows an example of the pulse length reduction with two selected front matching layers.
- Fig. 10 shows the effect on band of two other optimized front matching layers when the back-matching layer is made of epoxy + thermoexpandable particles cured at 110°C. In comparison with figure 8 a higher sensitivity is gained.
- 55 Fig. 11-14 are flowcharts of process for manufacturing a transducer assembly according to embodiments herein.

DETAILED DESCRIPTION OF A PREFERRED EMBODIMENT

[0031] Referring to figures 1 to 3, a conventional probe is illustrated therein. The probe comprises an ultrasound waves emitting and receiving head 1, which has a front side from which the ultrasound waves are emitted in the direction against a target, such as a body under examination, and on which the reflected ultrasound waves or incoming ultrasound waves impinge and are sensed. The ultrasound head 1 has a back side 3 which is opposite to the said front side and which is oriented towards the inside of a probe casing and towards means for supporting the probe head provided inside the probe casing.

[0032] The probe head 1 comprises, in an order starting from the back side of the said head towards the front side of the said head, which order corresponds also to the direction of propagation of the emitted ultrasound waves, a first layer 101 formed by an array of contact electrodes. Each contact electrode of this layer 101 of contact electrodes has a separate electric connection line to a corresponding contact pin on a contact termination provided along at least one edge of the layer of contact electrodes and indicated with 201. The layer 101 of contact electrodes is typically in the form of an array of at least electrically separated contact electrodes since each one of the said contact electrodes has the function of feeding the electric excitation signal to the associated transducer and of collecting the electric receipt signal from the associated transducer when the said transducer is mechanically excited by an impinging ultrasound wave. Some electrodes could be short circuited as in 1,25D, 1.5D or 1.75D probes.

[0033] On the layer formed by the array of contact electrodes, an array of piezoelectric elements 301 is laid. Each one of the piezoelectric elements forms an emitting and receiving transducer. Piezoelectric elements are typically fabricated from lead zirconate titanate (PZT), PZT-resin composite or Single Crystal material. The single transducers are each one coincident and in electric contact with one of contact electrodes of the layer 101. In a possible configuration, a further layer of conductive material 401 is laid on the layer 301 formed by the array of transducers. The conductive material of the layer 401 is in electric contact with each one of the said piezoelectric elements and is connected to ground potential by means of a contact termination 501. The layer 401 of conductive material forms the ground electrode of the transducers of the layer 301. The layer 401 may be in the form of an array of ground electrodes, but since the ground potential is common to every of the transducers of the layer 301 there is no need to provide separate ground electrodes for each transducer, so that the said layer 401 can be easily formed by a continuous layer of conductive material. Alternatively, the ground connections may be formed by a microscopic section wire 401' contacting elements belonging to a same row as shown in fig. 3. Other ground connection geometries are obviously possible, such as, for example, of the so-called wrap-around type.

[0034] On the array of piezoelectric material elements 301 matching layers are provided which are indicated with numerals 601 and 701 in fig. 1 and 2. These layers (two in the example of fig. 2, one in fig. 3) have the function of adapting the acoustic impedance of the piezoelectric elements to the acoustic impedance of the target. Normally two or three layers are used in order to provide a progressive stepwise adaptation, which also allows to maintain a sufficiently large bandwidth for the passing ultrasound waves. In each material, the acoustic impedance is given by the product of density times speed of sound and can be considered equivalent to the electrical impedance for an electrical circuit with many power transfer stages. The thickness of each matching layer generally follows the $\lambda/4$ rule, so they depend on their operating frequency (generally from 2 MHz to 12 MHz for standard imaging probes) and speed of sound in each material. Matching layer are generally manufactured from epoxy resin loaded with metallic particles. In the configuration with grounded conductive layer 401 (see fig. 1 and 2) the first matching layer 601 is generally placed above such grounded layer 401. In case of wiring connection 401' as in fig. 3, the first matching layer 601 is in direct contact with the piezoelectric elements 301.

[0035] Typically, the first matching layer 601 is made of a material having an acoustic impedance of about 5 to 12 MRayl and the last matching layer 701 has an acoustic impedance of about 2 MRayl.

[0036] As a last element, on the matching layer 701, an acoustic lens 801, typically of silicone rubber, is placed which forms the interface between the head of the probe 1 and the surface of a target body. The aim of such a lens is to focus the ultrasound beam in the elevation plane.

[0037] The contact terminations 201 and 501 of the layer 101 formed by the array of contact electrodes and of the layer 401 or wires 401' formed by the grounded conductive material are electrically and mechanically connected to a printed circuit board 4 which provides the necessary conductive tracks which are connected to a probe connection cable (not shown) via connector 8 and which cable connects the probe with an ultrasound apparatus as for example an ultrasound imaging apparatus.

[0038] A multi-element ultrasonic transducer array is generally formed from a block of piezoelectric material, which may be either a ceramic or a polymer. The block is cut or diced into one or more rows of individual elements to form the array. The element-to-element spacing is known as the "pitch" of the array and the spaces between individual elements are known as "kerfs." The kerfs may be filled with some filler material, generally a damping material having low acoustic impedance that blocks and absorbs the transmission of vibrations between adjoining elements, or they may be air-filled. The array of elements may be left in a linear configuration in which all of the elements are in a single plane, or the array

may be bent or curved for use as a convex or concave array.

[0039] Before the piezoelectric material is diced into individual array elements it is generally coated with metallic electrode material on the top (also referred to as the front, or transmit/receive side) and bottom of the bar. The electrodes on the top of the elements are conventionally connected to an electrical reference potential or ground, and individual conductors are attached to electrode areas on the bottom of the bar to electrically connect to each subsequently formed element. These conductors are then conventionally potted in an acoustic backing material as described, for example, in U.S. Pats. No. 4,825,115 which fills the space below the transducer elements and between the wires, and damps acoustic vibrations emanating from the bottom of the transducer array. Alternately, the conductors and backing material may be preformed in a block of backing material containing parallel spaced wires, which is then attached to the piezoelectric as described in U.S. Pat. No. 5,329,498 and U.S. Pat. No. 5,267,221. The piezoelectric bar and electrodes are then diced while attached to the backing material. As the bar is diced into individual elements, the metal plating is simultaneously cut into individual electrically separate electrodes for each transducer element. The transducer is completed by bonding front matching layers and the acoustic lens.

[0040] The result is a stack of layers starting from the backing 2 to the acoustic lens 801.

[0041] The backing material 2 acts both as a support and as a damping device for the back-travelling acoustic wave, to minimize reverberations and ringing. Backing material is generally a special hard rubber compound with poor thermal conductivity. A metallic, typically aluminium, block 3 acts as a support for the backing material 2. Where the term "backing" occurs it is understood as meaning a solid mass, of suitable geometry, on which the piezoelectric elements are mounted; when this component is excited by a voltage pulse, the oscillation is dampened and the reduction in the amplitude between successive oscillations depends on the material with which the component is combined. This base must therefore have particular acoustic properties in terms of impedance and absorption in order to obtain the desired level of attenuation.

[0042] This mechanism, nevertheless, causes the loss of a substantial part of the energy generated by the piezoelectric active material, because half of it is directed downward, towards the backing, and is lost into it being converted into heat.

[0043] Thus the idea of using a reflecting interface 5 between backing 2 and electrode 101 as shown in figures 4 to 6 to allow more energy to be directed towards the front face resulting in a stronger pulse, thus enhanced sensitivity, and reduced heating.

[0044] A small thickness (generally 1/4 of the incident wave wavelength) back-matching layer 5 interposed between backing 2 and electrode 101 modifies the bulk effective acoustic impedance as follows

$$Z_{\text{eff}} = (Z_{\text{layer}})^2 / Z_{\text{backing}}$$

[0045] As the backing acoustical properties are substantially modified, the back-matching layer has to be carefully chosen.

[0046] The prior art has mainly focused in implementing high Z de-matching layers (see for example US patent n. 7,621,028). This choice has some advantages, as a short pulse length and smaller ringing, but some drawbacks, for example for medium range frequencies (starting from 5-6 MHz) the bonding quality between piezoelectric metallization 101 and de-matching layer becomes critical. Furthermore, the quarter-wavelength resonance for piezo implies the use of small thickness piezoelectric material, more difficult to handle and manufacture for high frequency probes.

[0047] The inventors followed an opposite approach, i.e. studied the behaviour of back-matching layers having small impedance with half-wavelength resonance for piezo.

[0048] As some of such materials have themselves good adhesive properties, embodiments herein relate to the use of a back-matching layer also in the form of an adhesive layer for the creation of the subassembly piezo/backing with a reduced number of manufacturing steps.

[0049] The following table shows the characteristics of the studied material in terms of impedance of the back-matching layer (Z), impedance of the subassembly back-matching/backing (Z_{eff}) and reflection at the piezo interface (Reflection %).

	Z (MRayls)	Z _{eff} (MRayls)	Reflection %
Epoxy	3	1.3	70%
Epoxy + microspheres	2	0.56	85%
Epoxy + thermo-expandable particles	1.8 - 0.5	0.46-0.04	88%-99%

[0050] As it can be appreciated by looking at Fig. 7 showing the sensitivity comparison for various back-matching layer materials, it is possible to achieve high degree of sensitivity particularly if the impedance is kept very low.

[0051] As an example, a reduced Z material has been obtained by embedding in an epoxy matrix low density particles,

like hollow glass microspheres or thermo-expandable particles such as, for example, microcapsules encapsulating liquid low-boiling-point hydrocarbon in shells of thermoplastic resin like VCl₂-AN copolymer (chlorine containing shell), AN copolymer (chlorine-free shell). When the microcapsules added to the polymer, for example epoxy, are heated, the shells are softened and expanded with the pressure of gasified hydrocarbon while the polymer cures. A microcapsule expand into 50 to 100 times of its original volume (ballooning) and the cured polymer, where the heated microcapsules are dispersed, can have bulk density as small as 0.4 g/cm³ and acoustic impedance of 0.7-0.8 MRayl. By adjusting microcapsules concentration (% volume) in polymer and curing, the density/acoustic impedance of the material forming the back-matching layer can be fine-tuned.

[0052] For glass microspheres the particle size is determined by the manufacturer, while for thermo-expandable particles an optimization is possible by acting both on concentration (number of particles per unit volume) and curing heating process (final particle size). In our analysis a range of 0.5-1.8 MRayl impedance has been considered. In Fig 6 the curve labelled as Epoxy + thermo-expandable particles is related to the 0.8 MRayl acoustic impedance. Other results are intermediate between this and the Epoxy + microspheres curve (whose impedance is similar to the 1.8 max impedance considered in the thermo-expandable specimens).

[0053] Optimal back-matching layer thicknesses typically range from 1/3.5 to 1/8 of the central wavelength. Gains are between +6 and +10 dB.

[0054] Fig. 8 shows the effect on band of two optimized front matching layers with an epoxy back-matching layer as low Z amplifier. Comparison is made with the standard structure (the same front matching layers without any back-matching layer). The front matching layers are made of epoxy loaded with Tungsten particles in order to obtain intermediate acoustic impedances (about 8 MRayl and 3 MRayl, respectively). In this case, the back-matching layer is pure epoxy. The band obtained with the back-matching layer and front matching layers is typically in the range of 65-78%.

[0055] As it can be appreciated by looking at the figure, the presence of front matching layers has the effect of redistributing the energy to a wider spectrum of frequencies, resulting in a lower peak (i.e. lower sensitivity) either with the back-matching layer (indicated as low Z amplifier in the legend) or without any back-matching layer. Nevertheless, the curve with amplifier plus front matching layers remains always above the correspondent curve with no amplifier plus matching layers, indicating that there is a net energy gain. The sensitivity raise is +3dB in this case.

[0056] The resulting pulse is considerably shorter after the front layers application, as shown in fig 9. The -20 dB pulse length is reduced from 0.750 μs to 0.295 μs.

[0057] As a further example, Figure 10 shows the effect of front matching layers application over an acoustic stack with back-matching layer made of epoxy and thermo-expandable particles with acoustic impedance of 0.8MRayls.

[0058] Fig. 11 shows a flowchart of a process for manufacturing a transducer assembly according to embodiments herein, wherein a polymer, such as epoxy, is used for the back-matching layer.

[0059] At 901, Raw Materials (piezo, back-matching, backing) are provided.

[0060] At 902 the surface of the substrates (backing and/or piezo layer) are prepared, for example with plasma, chemical etching, with adhesion promoter or similar techniques for wettability increase and adhesion enhancement of back-matching material or piezo layer.

[0061] At 903 the back-matching material is casted either on the backing layer to realize a back-matching/backing subassembly or on the piezo material to realize a piezo/back-matching subassembly. In case of casting on piezo, bottom electrical connections are realized before casting.

[0062] At 907 backing with incorporated back-matching or piezo layer with incorporated back-matching is ready for acoustic stack assembly.

[0063] As shown in Fig. 12, further operations may include:

At 904 grinding of back-matching layer up to the desired thickness (905);

At 905 trimming of back-matching layer/piezo or back-matching layer/backing subassembly to the desired final size (906);

At 906 bonding either the piezo layer with the back-matching/backing subassembly or the piezo/back-matching subassembly with the backing layer (906).

[0064] Fig. 13 shows a flowchart of a process for manufacturing a transducer assembly according to another embodiment wherein thermo-expandable microcapsules or air bubble/glass microspheres are used for the back-matching layer.

[0065] At 111 Raw Materials (piezo, backing, polymer, thermo-expandable microcapsules or air bubble/glass microspheres) are provided.

[0066] At 112 the microcapsules/microspheres are added to the polymer based on the designed filling ratio by material weighting.

[0067] At 113 polymer and microcapsules are mixed, for example, with speedmixer in order to avoid air entrapment.

[0068] At 114 the surface of the substrates (backing and/or piezo layer) are prepared, for example with plasma, chemical etching, with adhesion promoter or similar techniques for wettability increase and adhesion enhancement of

back-matching material or piezo layer.

[0069] At 115 the mixture is casted to the backing material or to the piezo material. In case of casting on piezo, bottom electrical connections are realized before casting. Vacuum degassing can be advantageously adopted.

[0070] At 116 a curing step is provided to allow thermal expansion of the microcapsules.

[0071] At 117 the back-matching layer is grinded up to the desired thickness.

[0072] At 118 back-matching layer/piezo or back-matching layer/backing subassembly is trimmed to the desired final size.

[0073] At 119 backing with incorporated back-matching or piezo layer with incorporated back-matching is ready for acoustic stack assembly.

[0074] Alternatively, the back-matching layer can be produced as a standalone component and then bonded to the piezo layer or the backing. To such extent in the embodiment disclosed in Fig. 14:

At 121 Raw Materials (piezo, backing, polymer, thermo-expandable microcapsules) are provided.

At 122 the microcapsules are added to the polymer based on the designed filling ratio by material weighting.

At 123 polymer and microcapsules are mixed, for example, with speedmixer in order to avoid air entrapment.

At 124 the so obtained mixture is cast in a mold. Vacuum degassing can be advantageously adopted.

At 125 a curing step is provided to allow thermal expansion of the microcapsules.

At 126 the back-matching layer is grinded up to the desired thickness.

At 127 the back-matching layer is trimmed to the desired final size.

At 128 the back-matching layer ready for bonding with adhesives to realize an acoustic stack assembly.

[0075] All the process steps can be performed in any meaningful order and are not all necessary. For example grinding and trimming steps are obviously optional in all the embodiments herein disclosed as well as the surface preparation that can certainly be omitted. A variant could be to use adhesive properties of the back-matching layer to allow a direct bonding to piezo and/or backing. All without departing from the guiding principle of the invention disclosed above and claimed below.

Claims

1. A transducer assembly (1) operable to transmit ultrasonic energy in a desired direction towards a zone (801) adapted to be acoustically coupled to an object or area of interest, the assembly comprising:

a) a transducer layer (301);

b) a backing layer (2) disposed behind said transducer layer (301) with respect to the desired direction;

c) a back-matching layer (5) disposed between the transducer layer (301) and the backing layer (2) to reflect towards said transducer layer part of the ultrasonic energy directed from the transducer layer (301) to the backing layer (2),

characterized in that the back-matching layer (5) has an impedance less than the impedance of the transducer layer (301) and the transducer layer (301) has a thickness greater than a 1/4 of the wavelength of the ultrasound waves the assembly (1) is configured to generate.

2. Probe according to claim 1, wherein the transducer layer (301) has half wavelength thickness.

3. Probe according to claim 1 or 2, wherein the transducer assembly (1) comprises one or more front acoustic matching layers (601, 701) arranged as a stack starting from the transducer layer (301) towards the coupling zone, said front matching layers (601, 701) having a thickness less than half of the wavelength, particularly not greater than 1/3 of the wavelength, and being configured to compensate for increase in pulse duration of the ultrasound wave directed towards the desired direction caused by the low impedance of the back-matching layer (5).

4. Probe according to any preceding claim, wherein the back-matching layer (5) has an impedance less than 5 MRayl, particularly between 0.5 and 4 MRayl, typically between 0.6-2 MRayl, more typically between 0.7 and 1 MRayl.

5. Probe according to any preceding claim, wherein the back-matching layer (5) comprises or is formed by a material having adhesive properties.

6. Probe according to any preceding claim, wherein the back-matching layer (5) comprises a polymer such as epoxy,

powder/particle filled epoxy, polyurethanes, acrylics or the like.

5 7. Probe according to any preceding claim, wherein the back-matching layer (5) comprises air bubble/glass microspheres or thermic expandable particles to control the density of the material forming the back-matching layer.

8. Probe according to claim 6, wherein the thermic expandable particles comprise bubbles encapsulating liquid hydrocarbon in shells of thermoplastic resin like VCl₂-AN copolymer or AN copolymer.

10 9. Process for manufacturing a transducer assembly operable to transmit ultrasonic energy in a desired direction towards a zone adapted to be acoustically coupled to an object or area of interest, the process comprising:

- providing a transducer layer (301);
- providing a backing layer (2);
- providing a back-matching material (5) having acoustic impedance less than the acoustic impedance of the transducer layer (301),

characterized in further comprising:

- direct casting the back matching material (5) either on the backing layer (2) to realize a back-matching/backing subassembly or on the transducer layer (301) to realize a transducer/back-matching subassembly;
- bonding either the transducer layer with the back-matching/backing subassembly or the transducer/back-matching subassembly with the backing layer.

25 10. Process according to claim 9, further comprising:

- preparing the surface of the transducer layer or of the backing layer for wettability increase and adhesion enhancement of the back-matching material or transducer layer;
- grinding of the back-matching material to a pre-determined thickness.

30 11. Process according to claim 9 or 10, further comprising, before direct casting the back-matching material on the backing layer or on the transducer layer:

- providing air bubble/glass microspheres or thermo-expandable microcapsules;
- adding the microspheres/microcapsules to the back-matching material;
- mixing the back-matching material with the microspheres/ microcapsules.

40 12. Process according to claim 11, further comprising curing the back-matching material or the back-matching/backing subassembly or the transducer/back-matching subassembly to control the acoustic impedance of the back-matching material.

13. Process according to any claim 9 to 12, wherein the back-matching layer comprises one or more polymers, particularly epoxies, polyurethanes, acrylics or the like.

45 14. Process according to any claim 11 to 13, wherein the microcapsules encapsulate liquid low-boiling-point hydrocarbon in shells of thermoplastic resin like VCl₂-AN copolymer or AN copolymer.

50 15. Process according to any claim 12 to 14, wherein the curing step is performed at a temperature that allows the microcapsules to expand from 50 to 100 times their original volume to bring the density of the back-matching material less than 0.6 g/cm³, typically in the range 0.3-0.5 g/cm³, more typically equal or less than 0.4 g/cm³ and thus the acoustic impedance of the back-matching material less than 1 MRayl, typically between 0.6-0.9 MRayl, more typically between 0.7-0.9 MRayl.

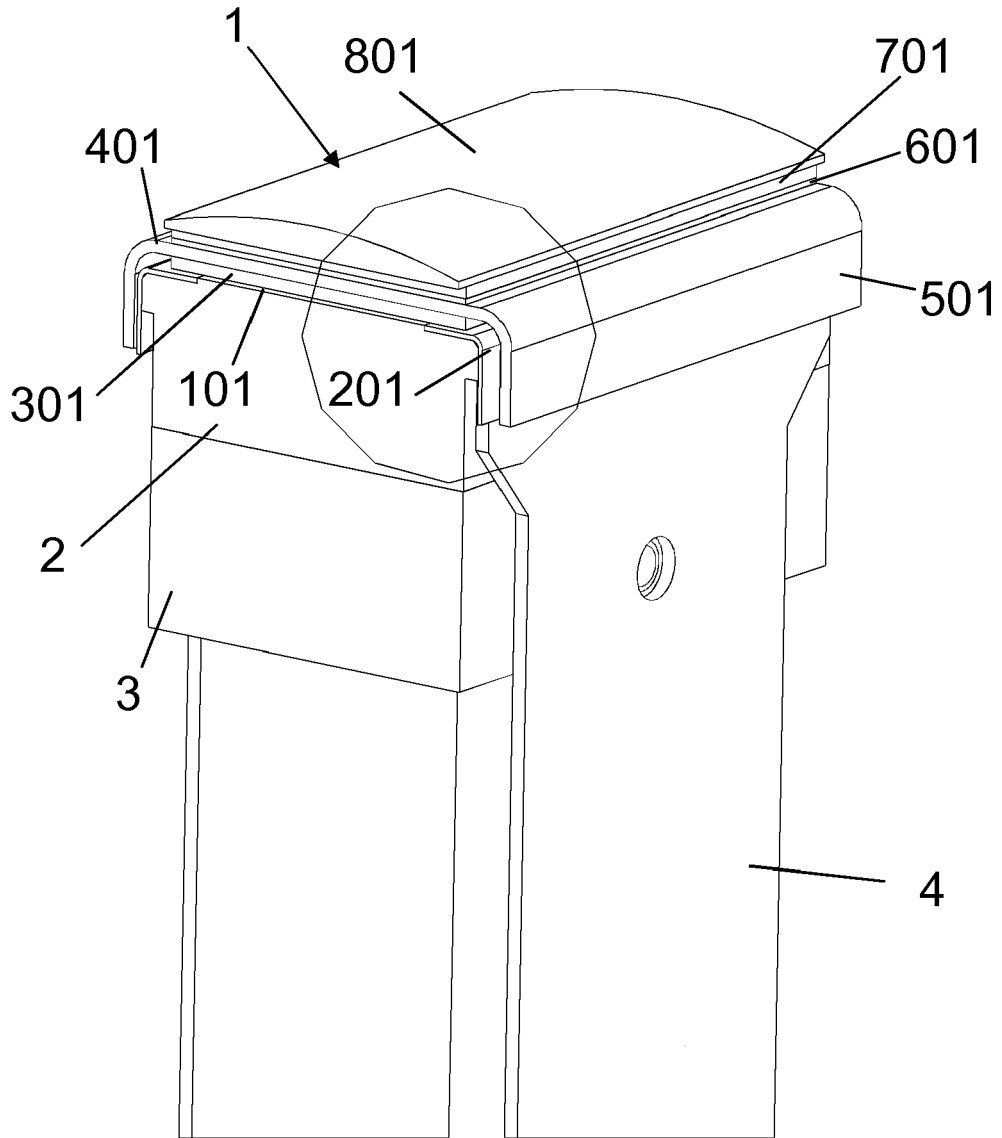


Fig. 1

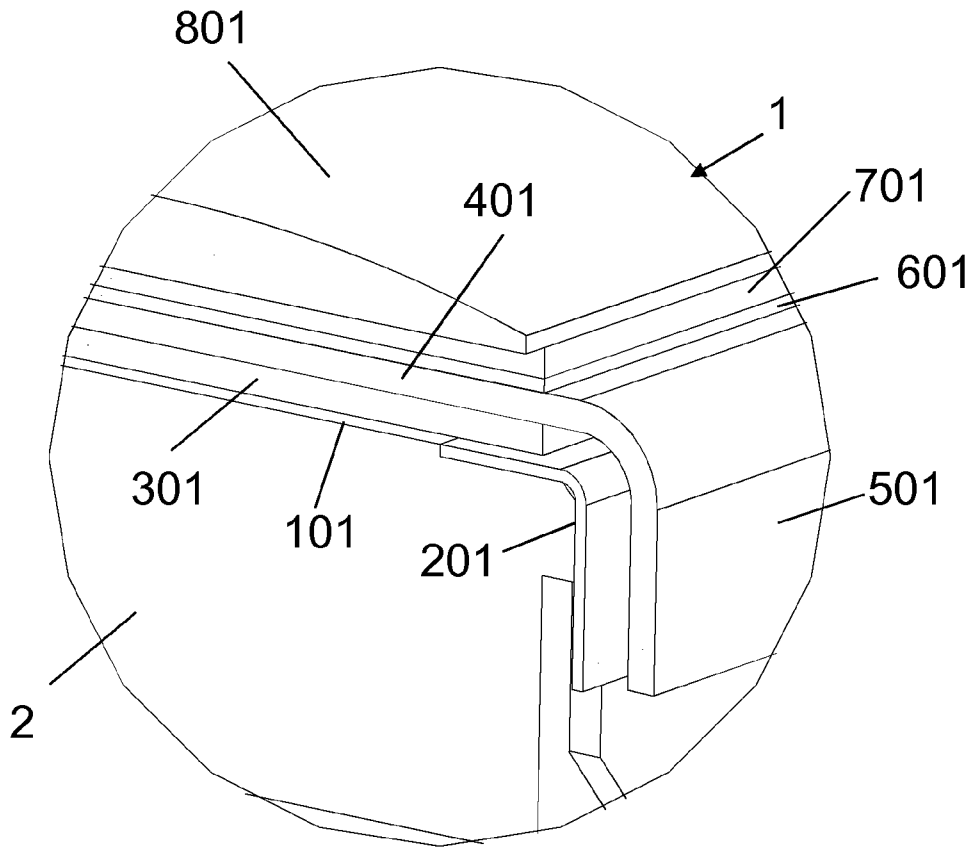


Fig. 2

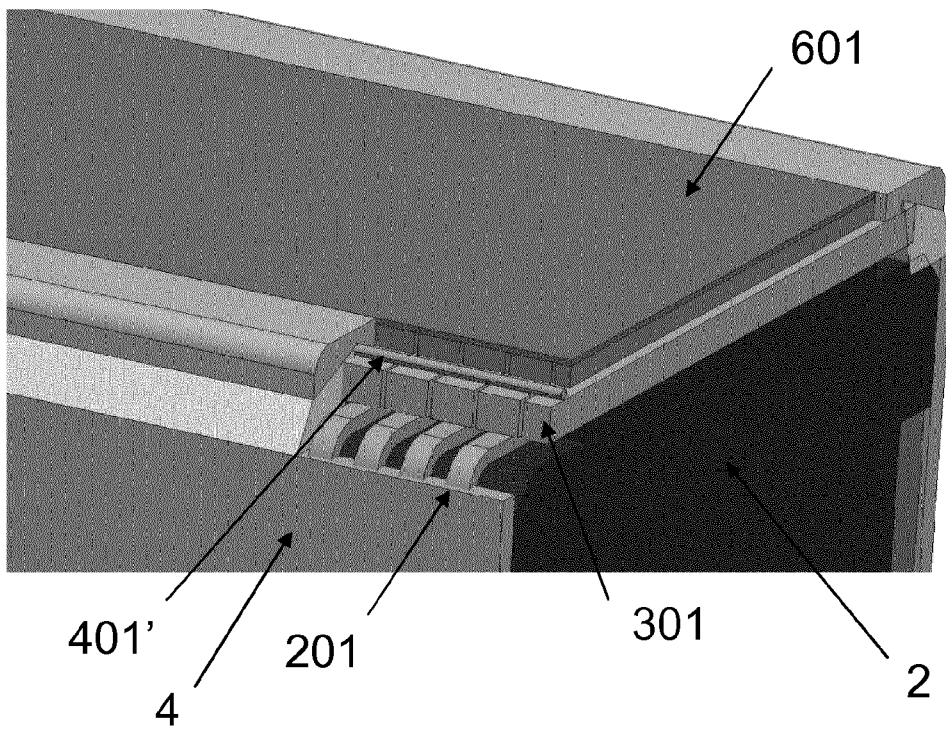


Fig. 3

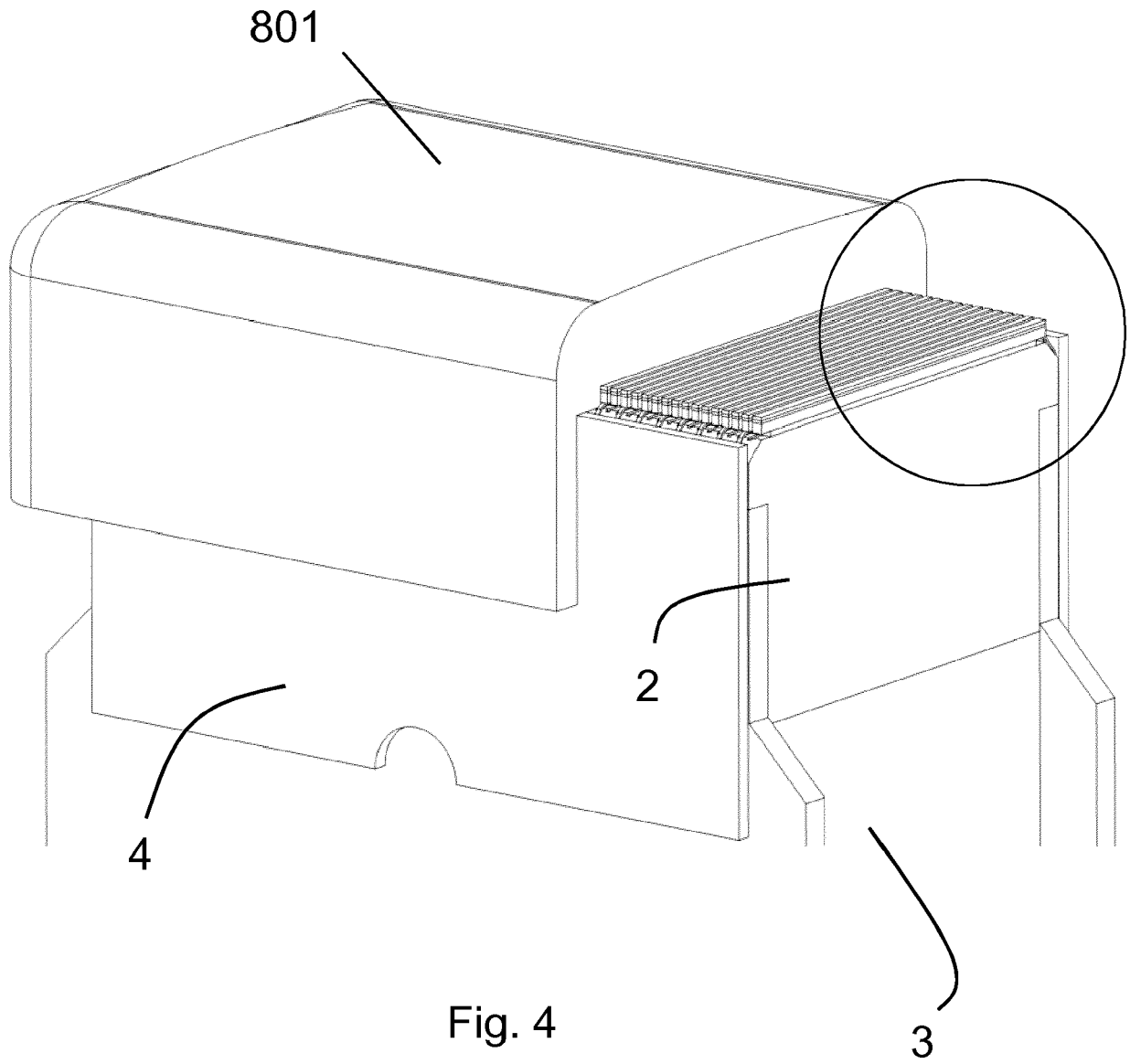


Fig. 4

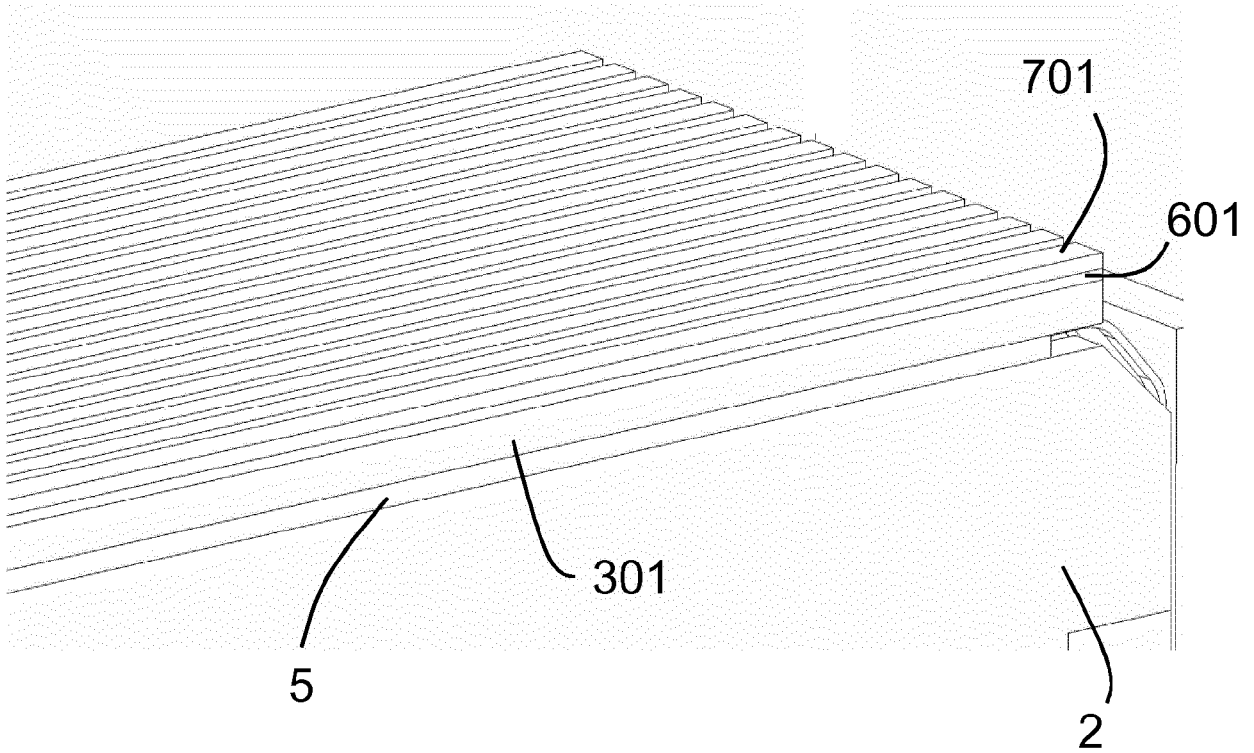


Fig. 5

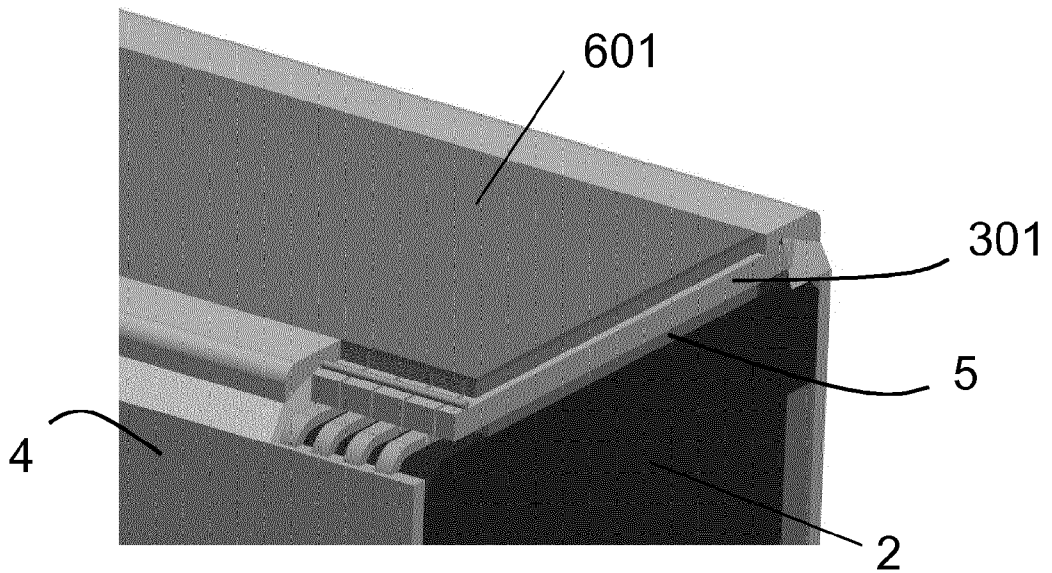


Fig. 6

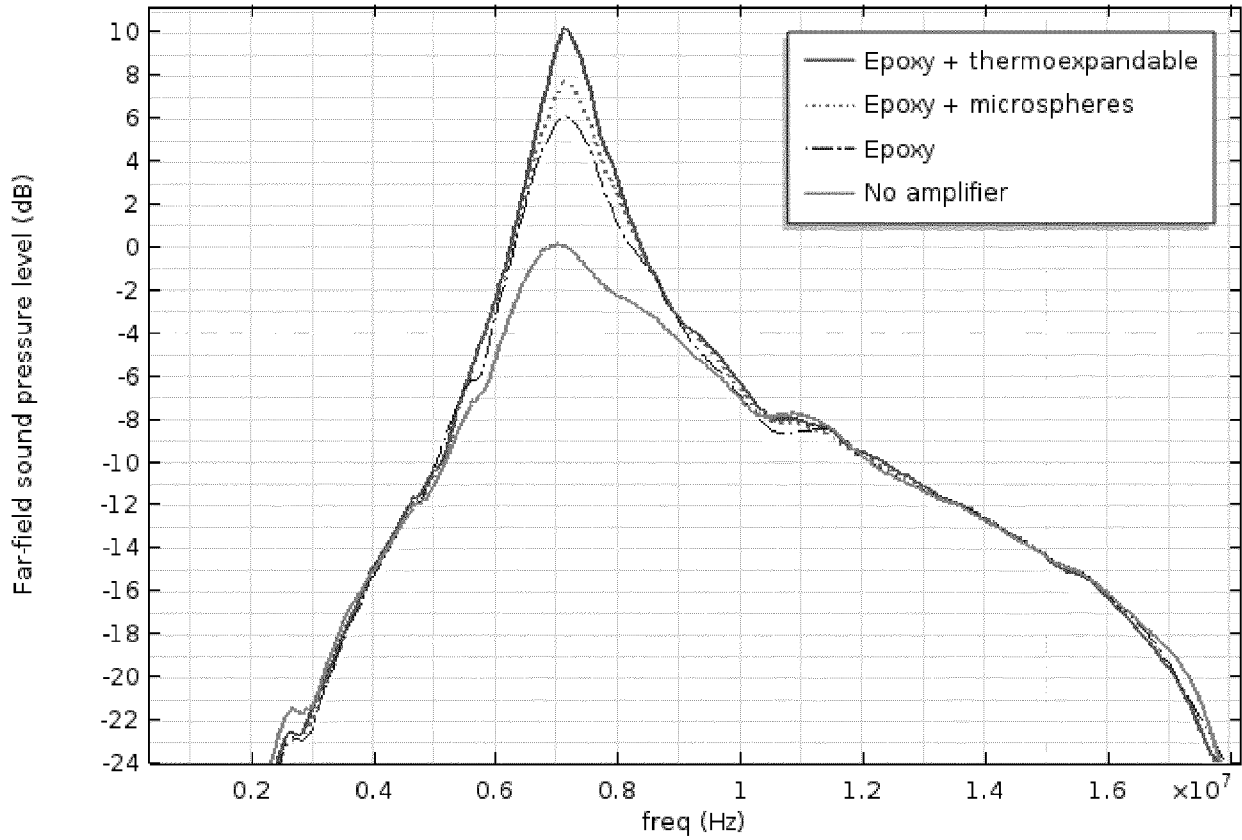


Fig. 7

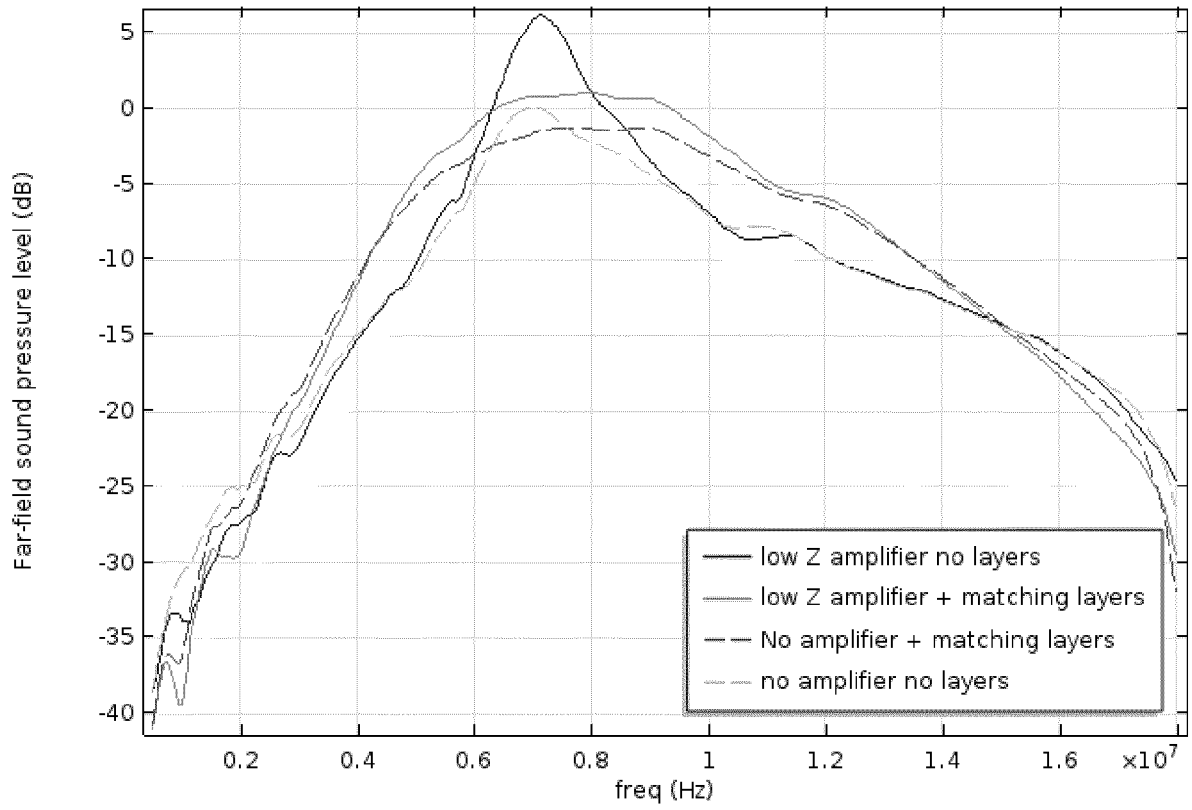


Fig. 8

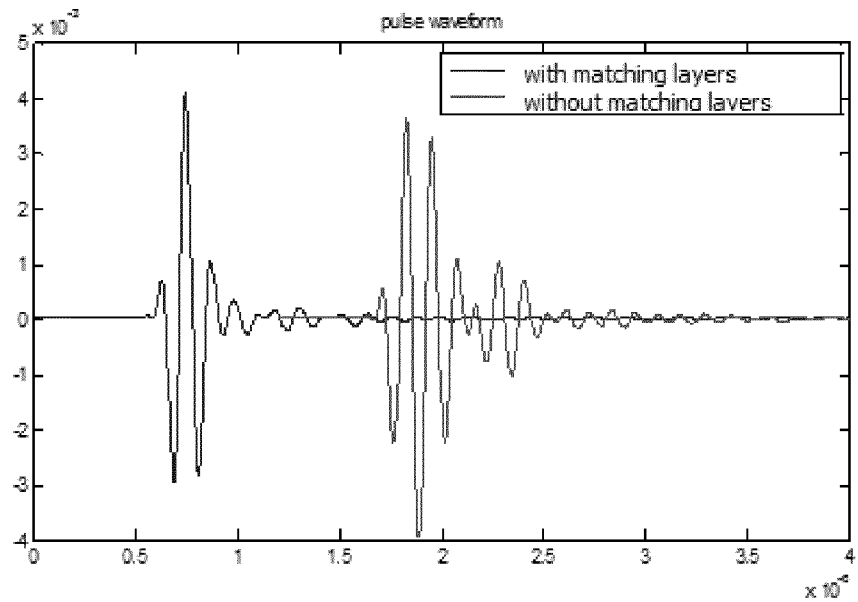


Fig. 9

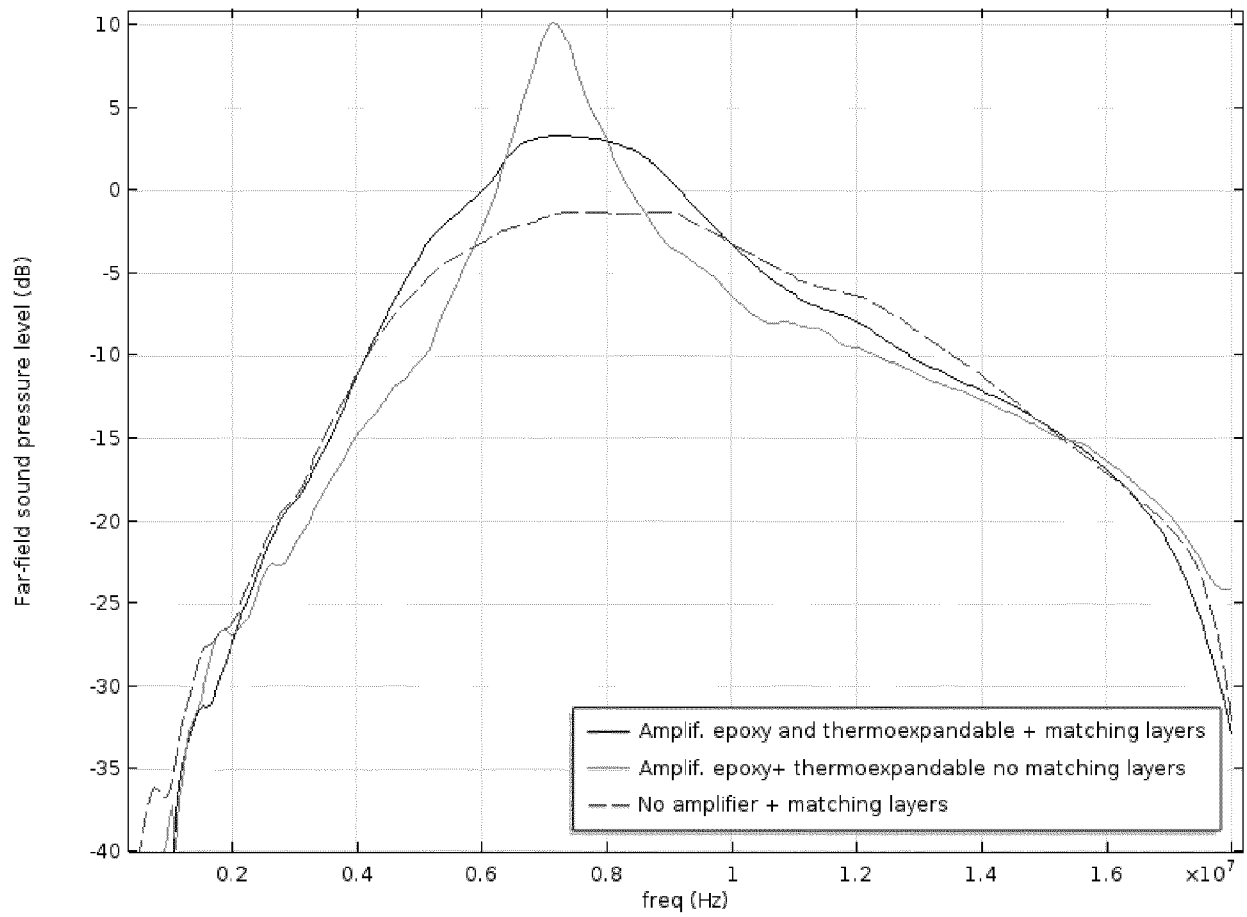


Fig. 10

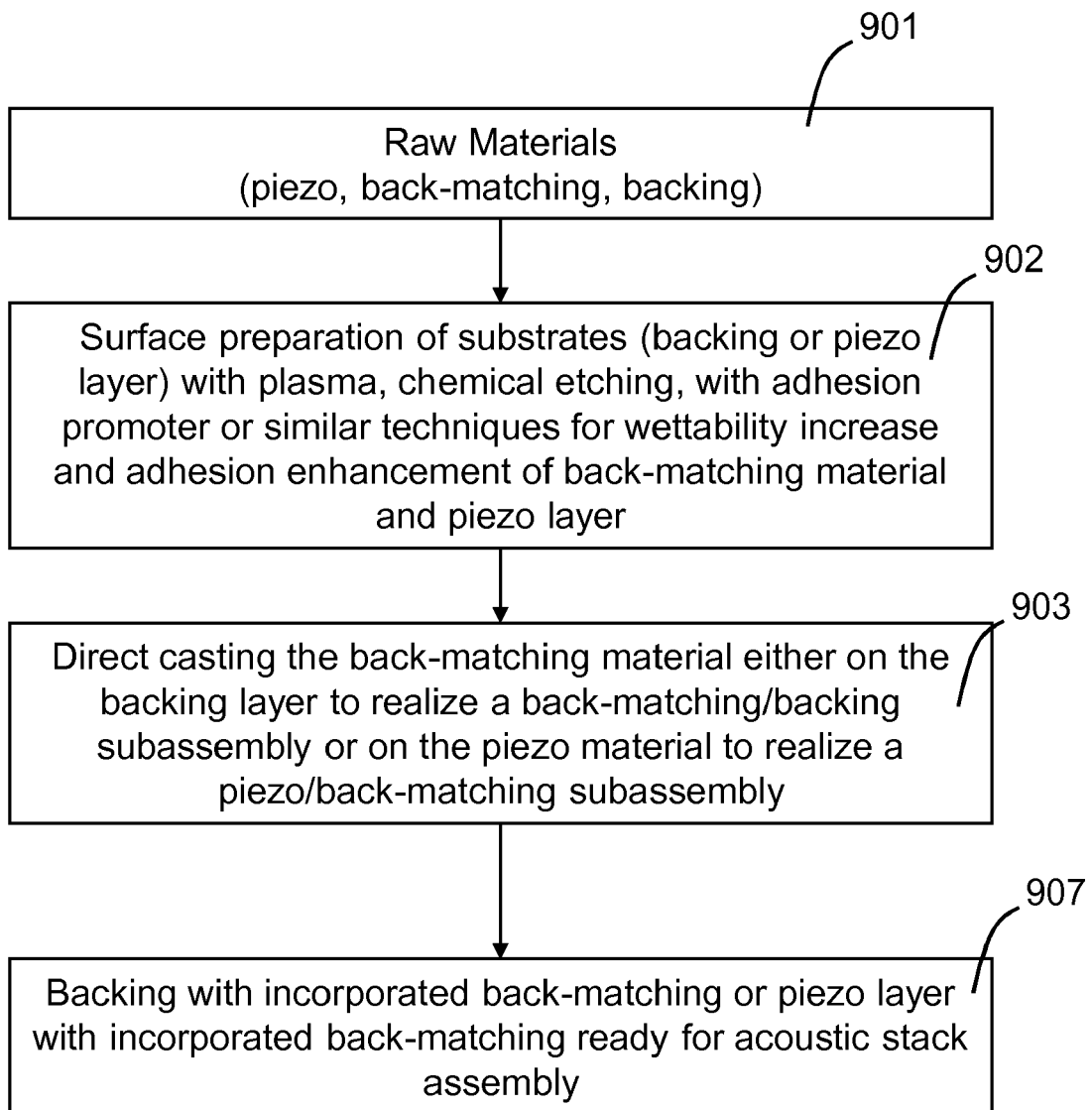


Fig. 11

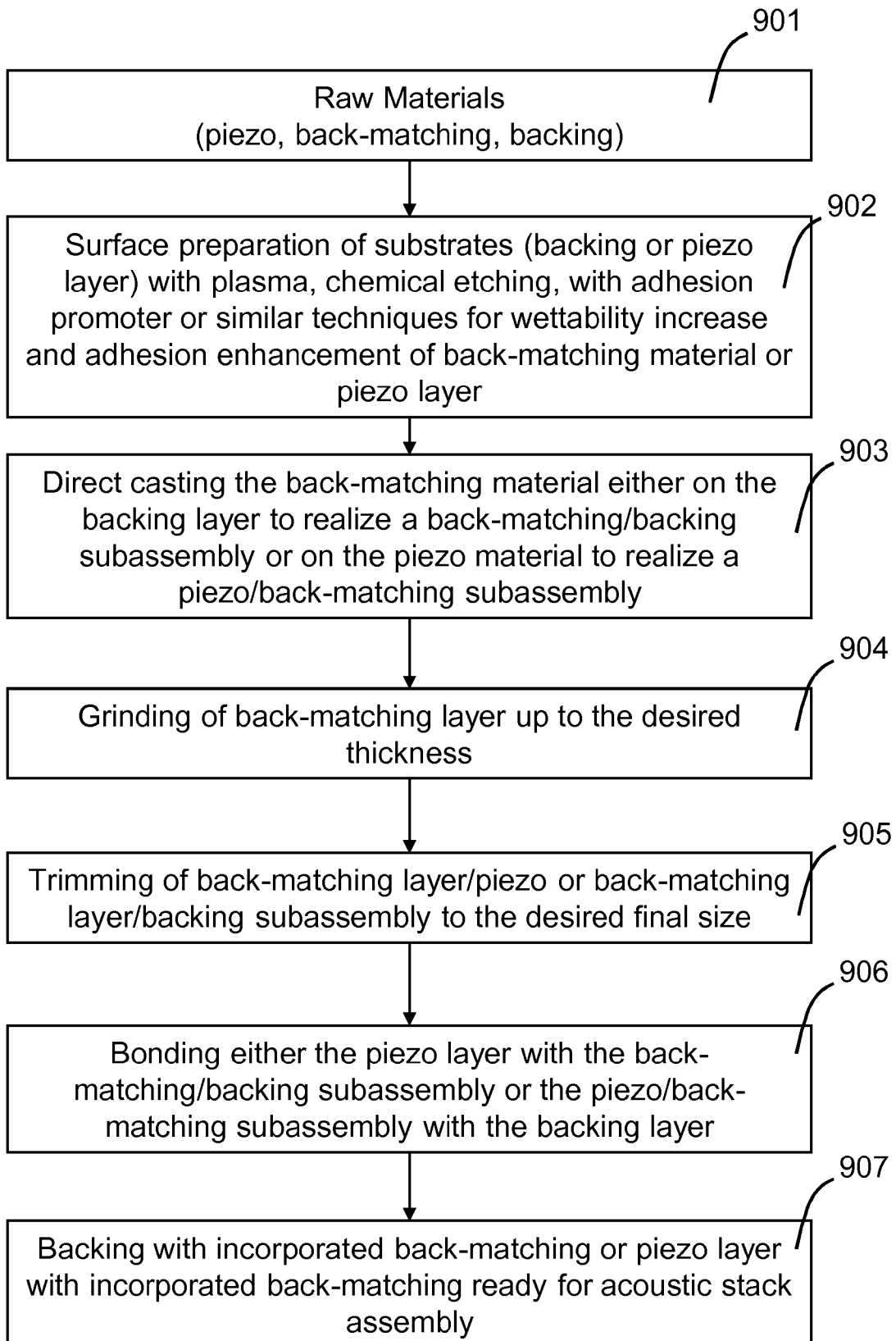


Fig. 12

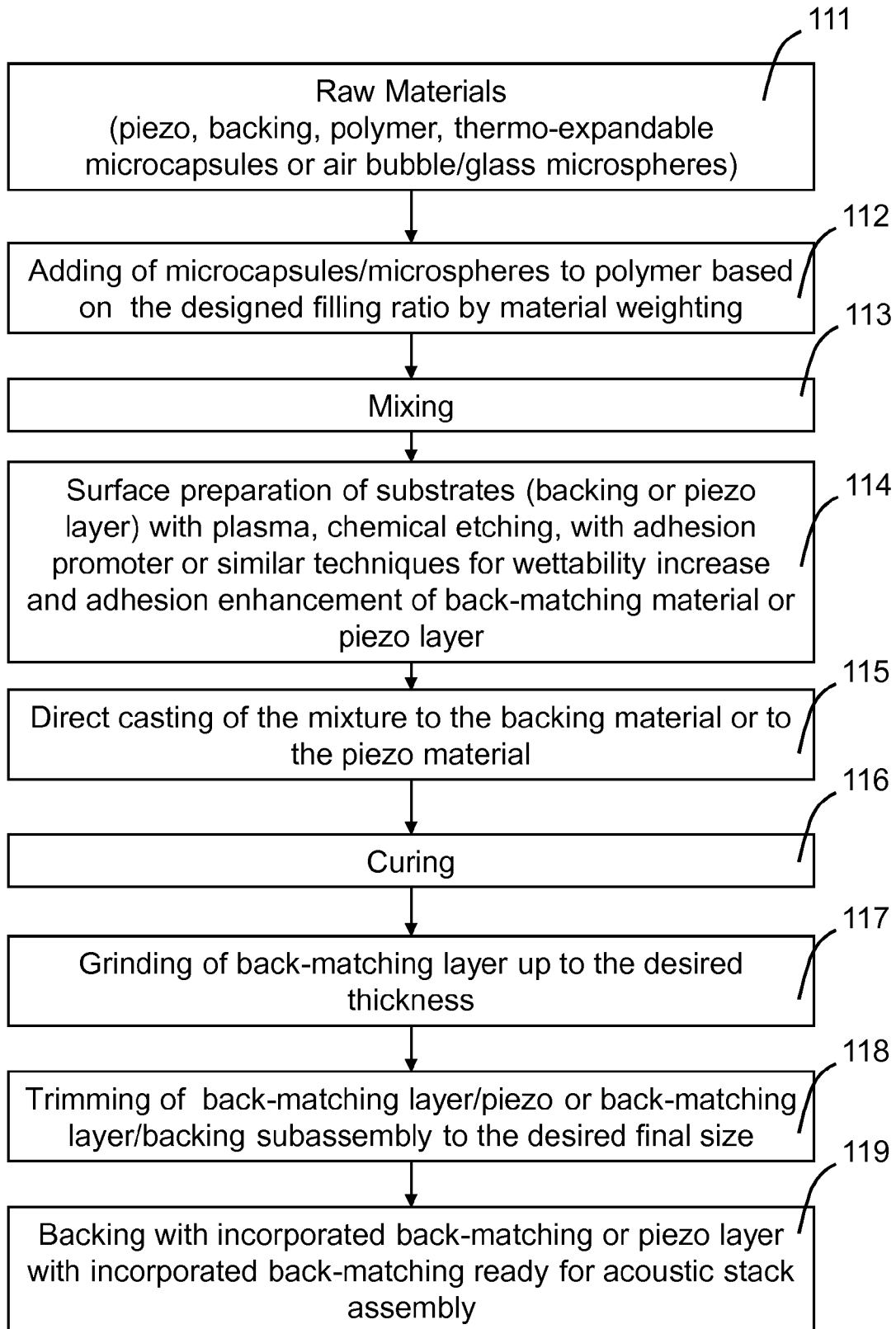


Fig. 13

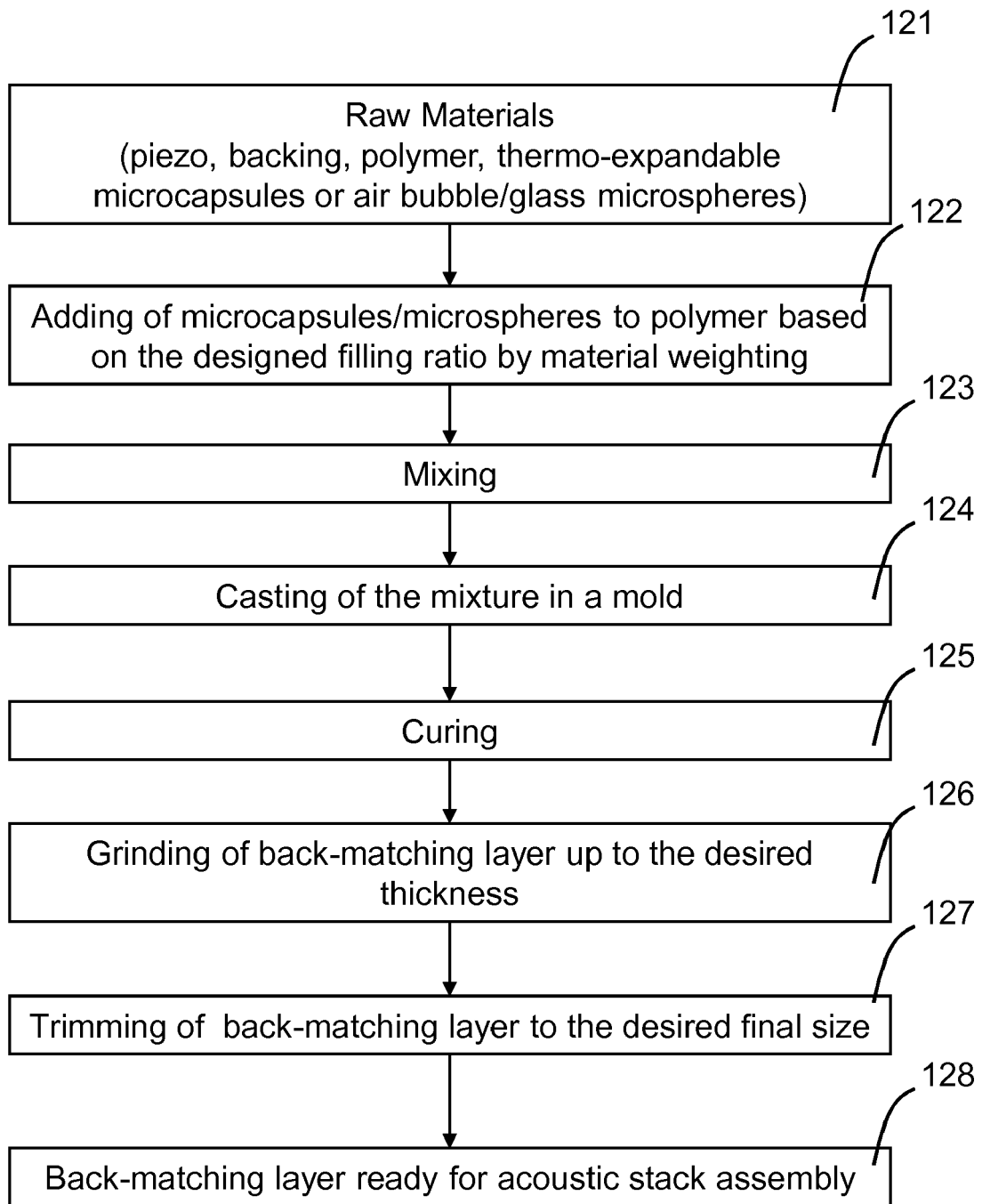


Fig. 14



EUROPEAN SEARCH REPORT

Application Number
EP 17 16 5437

5

10

15

20

25

30

35

40

45

50

55

DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (IPC)
X,D A	US 6 049 159 A (BARTHE PETER G [US] ET AL) 11 April 2000 (2000-04-11) * column 4, line 37 - line 64; figure 2 * -----	1-6,9, 10,13 7,8,11, 12,14,15	INV. A61B8/00 G10K11/20 B06B1/06 G10K11/02
X	US 4 771 205 A (MEQUIO CLAUDE R [FR]) 13 September 1988 (1988-09-13) * column 1 - column 4; figure 2 * -----	1-4,9	
			TECHNICAL FIELDS SEARCHED (IPC)
			A61B G10K B06B
The present search report has been drawn up for all claims			
Place of search Munich		Date of completion of the search 14 September 2017	Examiner Koprinarov, Ivaylo
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

EPO FORM 1503 03/02 (P04C01)

**ANNEX TO THE EUROPEAN SEARCH REPORT
ON EUROPEAN PATENT APPLICATION NO.**

EP 17 16 5437

5 This annex lists the patent family members relating to the patent documents cited in the above-mentioned European search report.
The members are as contained in the European Patent Office EDP file on
The European Patent Office is in no way liable for these particulars which are merely given for the purpose of information.

14-09-2017

	Patent document cited in search report	Publication date	Patent family member(s)	Publication date
	US 6049159 A	11-04-2000	NONE	
	US 4771205 A	13-09-1988	CA 1260603 A	26-09-1989
15			DE 3480968 D1	08-02-1990
			EP 0142178 A1	22-05-1985
			FR 2551611 A1	08-03-1985
			IL 72791 A	31-08-1988
20			JP H0640676 B2	25-05-1994
			JP S6084099 A	13-05-1985
			US 4771205 A	13-09-1988
25				
30				
35				
40				
45				
50				
55				

EPO FORM P0459

For more details about this annex : see Official Journal of the European Patent Office, No. 12/82

REFERENCES CITED IN THE DESCRIPTION

This list of references cited by the applicant is for the reader's convenience only. It does not form part of the European patent document. Even though great care has been taken in compiling the references, errors or omissions cannot be excluded and the EPO disclaims all liability in this regard.

Patent documents cited in the description

- US 6049159 A [0005]
- US 7621028 B [0008] [0046]
- US 4825115 A [0039]
- US 5329498 A [0039]
- US 5267221 A [0039]

专利名称(译)	超声波探头与声学放大器		
公开(公告)号	EP3384849A1	公开(公告)日	2018-10-10
申请号	EP2017165437	申请日	2017-04-07
[标]申请(专利权)人(译)	百胜集团		
申请(专利权)人(译)	ESAOTE S.P.A.		
当前申请(专利权)人(译)	ESAOTE S.P.A.		
[标]发明人	PALCHETTI PAOLO GRANDONI ANDREA CUSERI IOLANDA		
发明人	PALCHETTI, PAOLO GRANDONI, ANDREA CUSERI, IOLANDA		
IPC分类号	A61B8/00 G10K11/20 B06B1/06 G10K11/02		
CPC分类号	A61B8/4483 B06B1/0677 B06B1/0685 G10K11/02 B06B1/0681		
代理机构(译)	BESSI , LORENZO		
审查员(译)	KOPRINAROV , IVAYLO		
外部链接	Espacenet		

摘要(译)

一种换能器组件，其可操作以在期望的方向上朝向适于声学耦合到感兴趣的物体或区域的区域发射超声能量，该组件包括：- 换能器层；- 相对于所需方向设置在所述转换材料后面的背衬材料；- 设置在换能器层和背衬材料之间的背面匹配层，以朝向所述换能器层反射从换能器层引导到背衬材料的超声能量的一部分。背匹配材料的阻抗小于换能器层和换能器层的阻抗的厚度大于组件配置产生的超声波波长的1/4。还公开了一种用于制造换能器组件的方法。

$$\text{Reflection} = \frac{Z_{\text{layer}} - Z_{\text{piezo}}}{Z_{\text{layer}} + Z_{\text{piezo}}} \quad (\text{eq.1})$$